

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Accompanying Continuation Application under 37 CFR 1.53:

Prior Application: T. TANAKA et al
Serial No. 09/810,194
Filed: March 19, 2001
Group Art Unit: 1756
Examiner: K. Sagar

For: AN ELECTRON DEVICE MANUFACTURING METHOD,
A PATTERN FORMING METHOD, AND A PHOTOMASK
USED FOR THOSE METHODS

PRELIMINARY AMENDMENT

Commissioner for Patents
Alexandria, VA 22313

Sir:

Prior to examination, please amend the above application
as follows.